FILM DAMPING MODEL BASED ON THE DIRECT SIMULATION MONTE CARLO METHOD

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ASME DETC2007-34866 Las Vegas, NV, September 4-7, 2007





Gas damping is important in MEMS.

Motivation:

- Many micro/nano devices need high Q factor. Examples abound in
 - MEMS switches need high speed (high *Q*).
 - Resonant cantilever sensors need high responses.
 - MEMS gyroscopes.
 - MEMS accelerometers need controlled damping.
- Damping can reduce Q from several hundred thousands to several hundreds.
- Squeeze-film damping determines the dynamics of plates moving a few microns above the substrate.
- Molecular-dynamics-based models for predicting squeezed-film damping give different results.
- A new model based on the Direct Simulation Monte Carlo (DSMC) method shows potential for good accuracy.

•Needs experimental validation.

Objective:

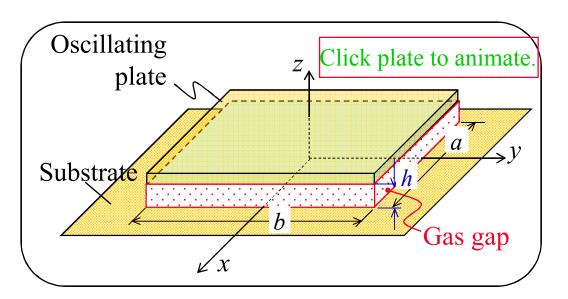
• Provide experimental validation of the DSMC-base squeezed-film damping model for rigid plates.

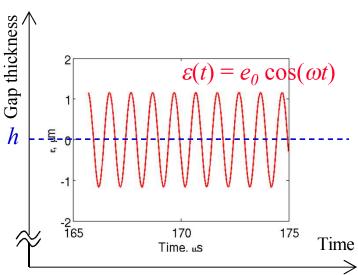




Squeezed fluid damps oscillation.

Plate oscillates at fequency ω .





The squeezed fluid between the plate and the substrate creates damping forces on the plate.





 Forces on moving plate from gas layer can be obtained from the linearized Reynolds equation

$$\frac{Ph^2}{12\mu}\nabla^2\left(\frac{p}{P}\right) - \frac{\partial}{\partial t}\left(\frac{p}{P}\right) = \frac{\partial}{\partial t}\left(\frac{z}{h}\right)$$

P = ambient pressure, Pa

h = gap size, m

 μ = viscosity, Pa s

p = pressure at (x,y), Pa

t = time, s

Assumptions:

- 1. Rigid plate
- 2. Small gap
- 3. Small displacement
- 4. Small pressure variation
- 5. Isothermal process





Instead of the trivial boundary conditions at the plate edges, GT introduced

$$P - p = \eta G(\hat{\mathbf{n}} \cdot \nabla p) + \zeta \left(\frac{12\mu U}{G}\right) \left(1 + \chi \frac{6\Lambda}{G}\right)^{-1}$$

DSMC simulations were used to determine correlations for the gas-damping parameters

$$\eta = \frac{0.634 + 1.572(\Lambda/G)}{1 + 0.537(\Lambda/G)} \qquad \chi = \frac{1 + 8.834(\Lambda/G)}{1 + 5.118(\Lambda/G)} \qquad \zeta = \frac{0.445 + 11.20(\Lambda/G)}{1 + 5.510(\Lambda/G)}$$

$$G = \text{gas film (gap) thickness. } \Lambda/G \text{ is modified Knudsen number}$$
 $\Lambda = \frac{2-\alpha}{\alpha}\lambda$ $0 \le \Lambda/G \le 1$ $\alpha = \text{accommodation coefficient. (For this test device } a = 1).$





Present measurement was done on an oscillating plate.

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- Structure is electro-plated Au.
- Thickness around 5.7 µm.
- Substrate is alumina.

$$A = 29717 (\mu m)^2$$

 $a = 154.3 \ \mu m$

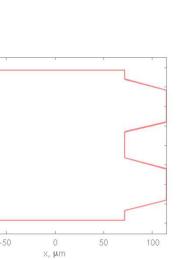
Air gap between plate and substrate. Mean thickness = $4.1 \mu m$.

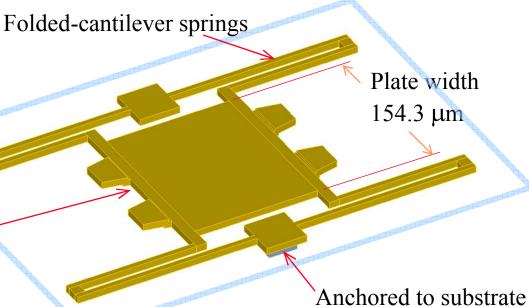
40

-40

-80

y, tum



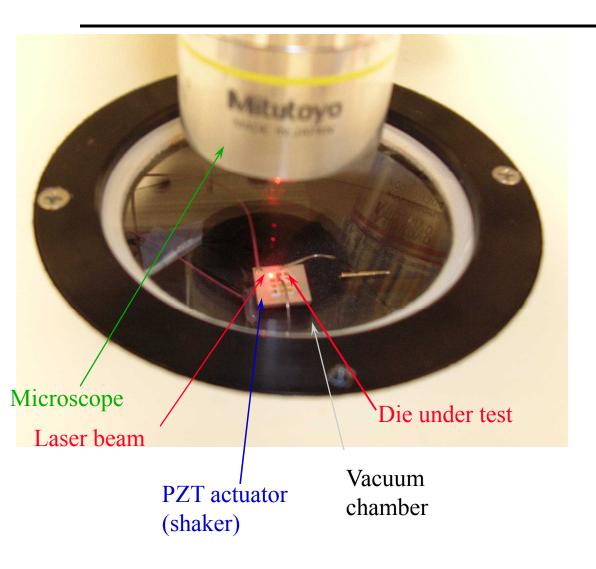






Measurement uses LDV and vacuum chamber.

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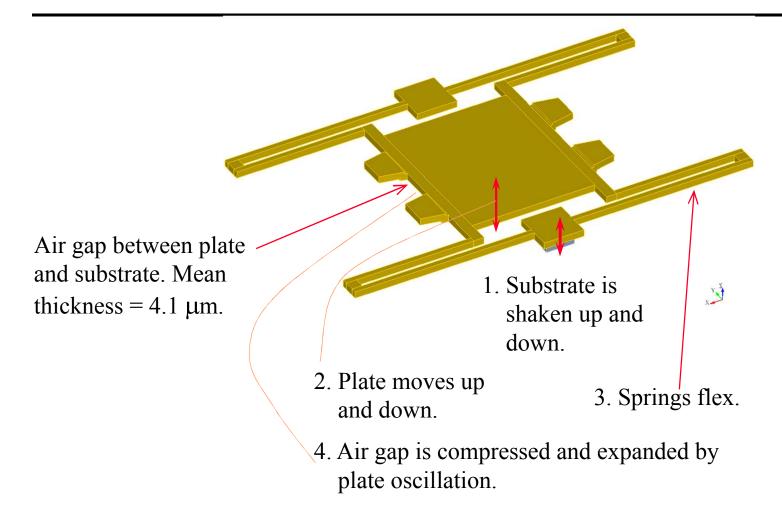
- Substrate (base) was shaken with piezoelectric actuator.
- Scanning Laser Doppler Vibrometer (LDV) measures velocities at base and at several points on MEMS under test.





Oscillating plate was shaken through its support.

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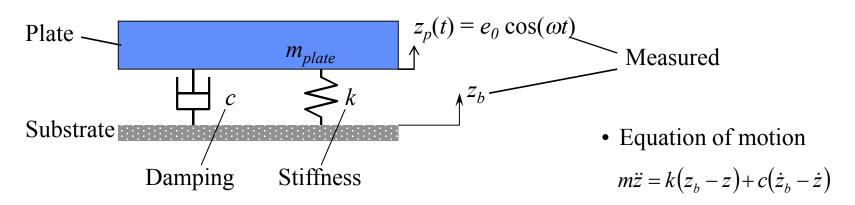






The rigid plate test structure can be modeled as SDOF.

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• Frequency response function (FRF) from base displacement to plate displacement:

$$\frac{Z_p(\omega)}{Z_b(\omega)} = \frac{m\omega^2}{-m\omega^2 + j\omega c + k_s} + 1$$
 (Measured)

• Frequency response function (FRF) from base displacement to gap expansion:

$$\frac{Z(\omega)}{Z_b(\omega)} = \frac{Z_p(\omega) - Z_b(\omega)}{Z_b(\omega)} = \frac{m\omega^2}{-m\omega^2 + j\omega(\beta + c_s) + k_s}$$
Squeeze-film damping

Non-SF damping

- obtained from measurement at vacuum.
- will be subtracted from measured data.



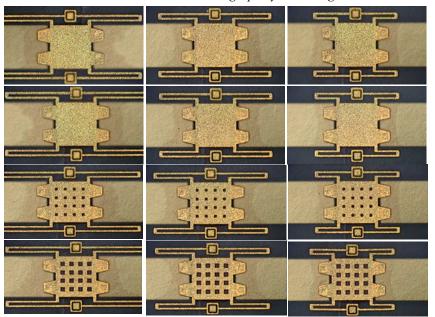
Measurement on array of plates gave natural frequency and damping.

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Numbers in tables correspond to

position in array

Des. and Fab. by Chris Dyck, SNL Photograph by Carl Diegert, SNL



Undamped Natural Frequency f_1 , Hz		
10509	17350	21721
12003	18507	29071
11922	17902	30405
12951	20561	31300

- The first two rows were designed to be identical.
- Differences were due to fabrication tolerance.

ζ_1 for $P = 83.3$ kPa, % of Critical		
10.05	7.61	5.35
10.36	7.72	5.93
9.52	8.19	5.06
9.51	8.60	5.99

ζ_1 for $P = 8$ kPa		
5.58	3.57	2.26
4.93	3.56	2.58
5.28	4.03	2.13
5.32	3.84	2.63

ζ_1 for $P = 0.8$ kPa		
1.03	0.59	0.49
1.00	0.79	0.41
1.01	0.64	0.38
0.81	1.16	0.38

ζ_1	ζ_1 for $P = 8$ Pa		
0.49	0.12	0.20	
0.30	0.34	0.09	
0.13	0.11	0.12	
0.20	0.32	0.13	

ζ_1 for $P = 0.8$ Pa		
0.54	0.07	0.10
0.12	0.28	0.09
0.15	0.12	0.12
0.50	0.41	0.19
Laboratories		

• Models predict *damping factor c* in the equation of motion

$$m_{eff}\ddot{z} + \beta \dot{z} + kz = f_{ext}(t)$$

• Measurement method gives *damping ratio* ζ in the equation of motion

$$\ddot{z} + 2\zeta \omega_n \dot{z} + \omega_n^2 z = \hat{f}_{ext}(t)$$

• To compare prediction with measurement, use the relationship between c and ζ

$$\beta = 2m_{eff}\omega_n\zeta$$

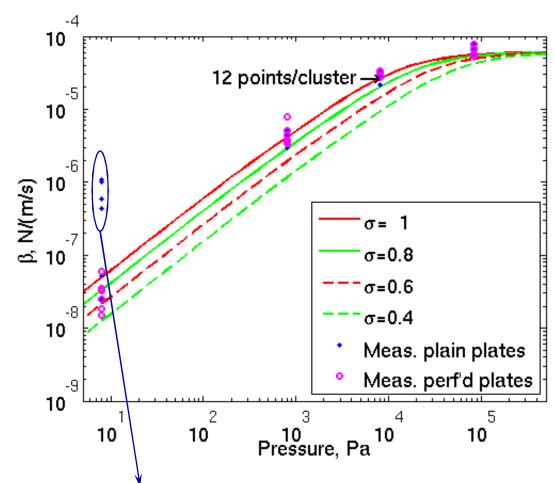
$$m_{eff} = m_{plate} + 4 \times 0.37 m_{spring}$$

$$h_{plate}$$
 = plate thickness, m
 ω_n = natural frequency, rad/s
 m_{eff} = effective mass, kg





slide 12



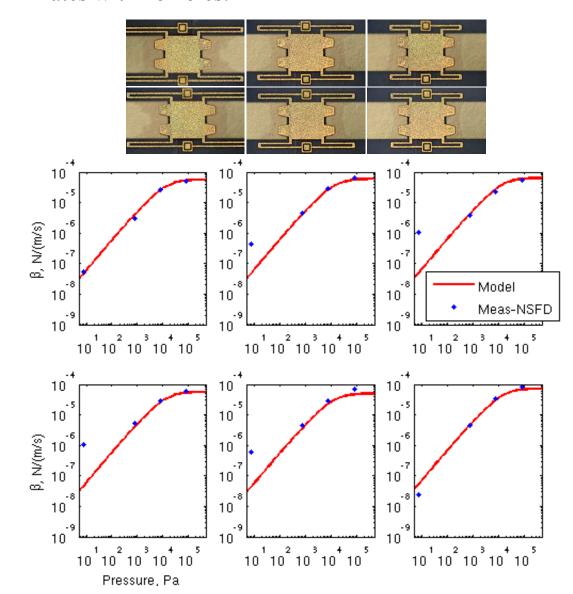
Hanning window, needed to reduce leakage in signal processing, distorted damping measurement.

- Lower pressure results in lower damping, as expected.
- Curve-fitting was not reliable at 6 mT.
 - Very high *Q* means very few data points around resonance.
- $\sigma = 1$ fits measured data the best.



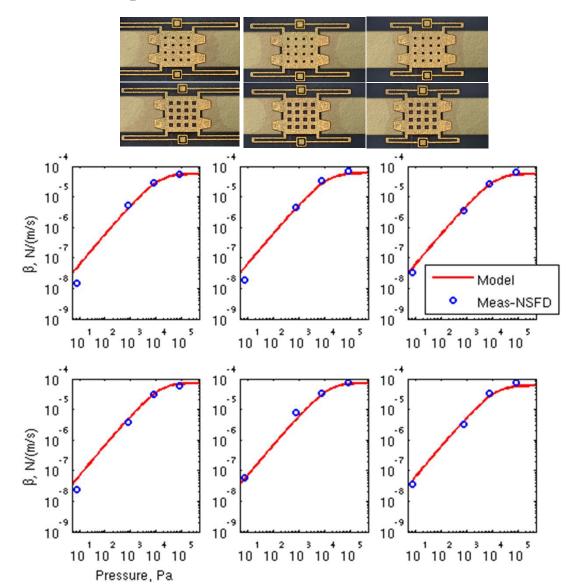


Plates with no holes.



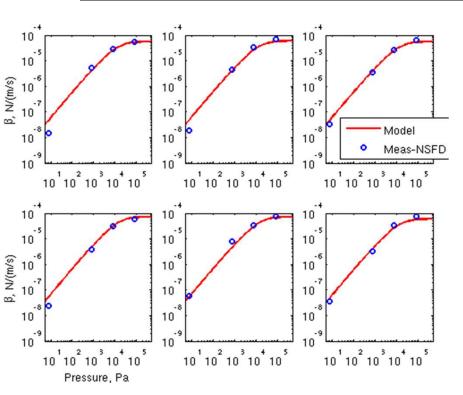


Perforated plates.





Conclusions:



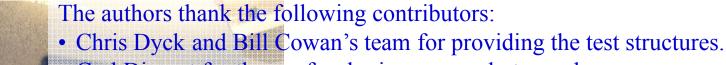
- Model and experimental results are compared for a MEMS plate oscillating above an adjacent substrate with a gas-filled gap between.
- The results indicate that the damping coefficient decreases almost linearly with pressure on the log-log scale below 8 kPa.
- The model and experiment agree to within the experimental uncertainty if an accommodation coefficient of unity is employed, which is a reasonable value based on previously reported values.
- Small perforation holes do not result in deviation from prediction without holes.
- Better experiment control is needed to reduce the data scatter at low pressure (rarefied gas regime).





Acknowledgment





Carl Diegert for the confocal microscope photographs.

• Jim Redmond and Steve Kempka for technical guidance and programmatic support.



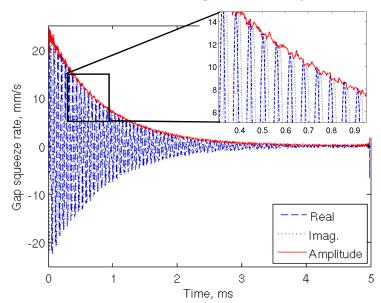
Thank you!

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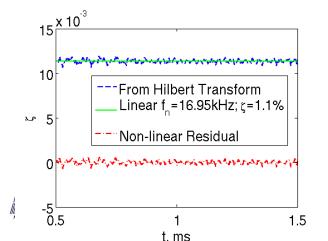




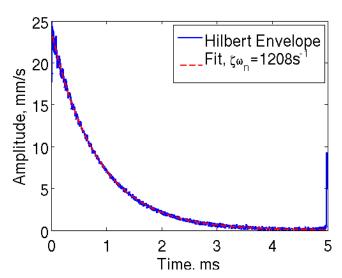
1. Hilbert transform gives decay envelope.



3. Damping is constant with time.



2. Exponential fit gives damping times natural frequency.



4. For this case (P=3830milliTorr), both experimental modal analysis (frequency domain fit) and free decay curve-fitting (time domain fit) give damping ratio $\zeta = 0.0011$

